

ABSTRACT

To provide a technique which cleans an attracting face of a mechanism for electrostatically attracting an object to be processed inside a vacuum processing apparatus and keeps its attracting force constant. The method of the present invention is for cleaning an attracting face 3a of a hot plate 3 which holds the object to be processed inside a vacuum processing chamber 2 through electrostatic attraction. The invention method includes a step of cleaning the attracting face 3a of the hot plate 3 by applying a high-frequency electric power of 13.56MHz to a metallic base 6 arranged under and near the hot plate 3 in a state in which a cleaning gas G is introduced into the vacuum processing chamber 2.